

Form PTO-1449 <i>OCT 25 2002</i> U.S. PATENT & TRADEMARK OFFICE	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MI22-2042	SERIAL NO. 09/579,402
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		APPLICANT: Kei-Yu Ko	
		FILING DATE May 25, 2000	GROUP 2815

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
EL	AA	5,269,879	12/14/93	Rhoades et al.	156	643	
EL	AB	5,298,465	03/29/94	Levy	437	225	
EL	AC	5,658,425	08/19/97	Halman et al.	438	620	10/29/00 RECEIVED OCT 29 2002 MAIL ROOM
EL	AD	5,685,914	11/11/97	Hills et al.	118	723	
EL	AE	5,780,338	07/14/98	Jeng et al.	438	253	
EL	AF	5,783,496	07/21/98	Flanner et al.	438	743	
EL	AG	5,817,579	10/06/98	Ko et al.	438	740	
EL	AH	5,830,807	11/03/98	Matsunaga et al.	438	714	
EL	AI	5,871,659	02/16/99	Sakano et al.	216	79	
EL	AJ	5,908,320	06/01/99	Chu et al.	437	743	
EL	AK	5,946,568	08/31/99	Hsiao et al.	438	253	
EL	AL	6,074,488	06/13/00	Roderick et al.	118	728	

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
EL	AM	0 680 084 A1	28.04.95	EPO (Texas Instruments Inc.)				
EL	AN	WO 98/49719	05.11.98	WIPO (Micron Technology, Inc.)				
	AO							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

EL	AP	Abatchev et al., Study of the Boron-Phosphorous Doped and Undoped Silicate Glass Etching in
		CHF ₃ /Ar Plasma, 96 ELECTROCHEM. SOC. PROCEEDINGS, No. 12, pp. 522-530 (1996).
	AQ	

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PATENT & TRADEMARK OFFICE*

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
El	AA	6,074,958	06/13/00	Tokunaga et al.	438	724	<i>TC RECEIVED OCT 29 2000 MAIL ROOM</i>
EL	AB	6,117,788	09/12/00	Ko	438	706	
EL	AC	6,117,791	09/12/00	Ko et al.	438	723	
EL	AD	6,121,671	09/19/00	Ko et al.	257	644	
EL	AE	6,153,490	11/28/00	Xing et al.	438	396	
EL	AF	6,159,862	12/12/00	Yamada et al.	438	712	
EL	AG	6,165,880	12/26/00	Yaung et al.	438	592	
EL	AH	6,171,970 B1	01/09/01	Xing et al.	438	706	
EL	AI	6,174,451 B1	01/16/01	Hung et al.	216	67	
EL	AJ	6,183,655 B1	02/06/01	Wang et al.	438	723	
EL	AK	6,254,966 B1	07/03/01	Kondo	428	156	
EL	AL	6,337,285 B1	01/08/02	Ko	438	714	

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
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	AN						
	AO						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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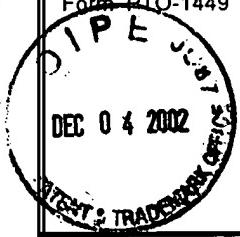
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Form PTO-1449 <i>O I P E S C</i> OCT 25 2002 PATENT & TRADEMARK OFFICE		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)			ATTY. DOCKET NO. MI22-2042		SERIAL NO. 09/579,402		
			APPLICANT: Kei-Yu Ko						
			FILING DATE May 25, 2000		GROUP 2815				
U.S. PATENT DOCUMENTS									
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate	
<i>CL</i>	AA	6,432,833 B1	08/13/02	Ko		438	714		
<i>CL</i>	AB	6,458,685 B1	10/01/02	Ko et al.		438	621		
<i>CL</i>	AC	09/532,088		Ko				03/21/2000	
<i>CL</i>	AD	09/945,508		Ko				08/30/2001	
	AE								
	AF								
	AG								
	AH								
	AI								
	AJ								
	AK								
	AL								
FOREIGN PATENT DOCUMENTS									
		Document Number	Date	Country		Class	Subclass	Translation	
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	AO								
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
	AP								
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CL	AA	5,883,436	03/16/99	Sadjadi et al.	257	760	
CL	AB	6,277,758 B1	08/21/01	Ko	438	706	
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
CL	AK	61-133555	12.03.84	Japan (NEC, Ltd.)			X	
CL	AL	0 465 044 A2	19.06.91	EPO (AT&T)				
CL	AM	0 496 614 A1	23.01.92	EPO (NEC Corp.)				
CL	AN	0 763 850 A1	30.08.96	EPO (Applied Materials)				
	AO							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

CL	AP	W.G.M. van den Hoek et al., <i>Isotropic plasma etching of doped and undoped silicon dioxide for contact holes and vias</i> , 7 J. VAC. SCI. TECHNOL. A., No. 3, pp. 670-675 (May/June 1989).					
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